

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Patent Application of

Yukiyasu SUGANO et al.

Serial No. 09/478,812

Filed: January 7, 2000

For: Process For Producing Thin  
Film Semiconductor Device and  
Laser Irradiation Apparatus

Group Art Unit: 2815

Examiner: E Lee

TECHNOLOGY CENTER 2800  
NOV 26 2001#13  
RECEIVED  
11-28-01  
T. FlowersPETITION TO EXTEND TIME FOR RESPONSE  
TO WITHIN THE SECOND EXTENDED MONTHCommissioner for Patents  
Washington, D.C. 20231

Sir:

The applicant, through its attorneys, hereby petitions to extend time for response to the final Official Action of June 21, 2001 to within the second extended month. The Commissioner is authorized to charge \$400.00 to Deposit Account 18-0013 to cover the petition fee for a large entity.

The Commissioner is hereby authorized to charge any additional fees associated with this communication or credit any overpayment to Deposit Account No. 18-0013. A duplicate copy of this letter is enclosed for that purpose.

Respectfully submitted,

DATE: November 21, 2001

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